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Corrosion and Etching at Micro/Nanoscale

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Deadline for manuscript submissions:

closed (31 December 2021)

Message from the Guest Editors

Dear Colleagues,

I am very glad to invite you to contribute to this Special Issue of Micromachines. Corrosion and etching at micro (nano) scale is an important topic in several fields, from the fabrication of sensors and membranes to investigations of the properties of micro- and nano-composites. The study of this phenomena is essential to acquire knowledge on the physical and mechanical properties of synthesized materials and their resistance to corrosion. This Special Issue is devoted to the review and discussion of all theoretical and practical aspects of these processes. Both experimental and theoretically based contributions related fabrication via etching processes and characterization of corrosion resistance in microdevices and composites are welcome.

Dr. Giorgio Luciano Dr. Małgorzata Norek *Guest Editors*













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Editor-in-Chief

Message from the Editor-in-Chief

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